

A B S T R A C T

A storage system useful for processing large amounts of data is provided.

5 When a wafer cassette to be accessed that includes
a first semiconductor wafer is not connected to a slot
of a host apparatus and is stored in a wafer cassette
stocker, the host apparatus causes a wafer cassette
transport device to transport the wafer cassette to be
accessed, to the slot of the host apparatus, and to
10 connect it thereto. When the wafer cassette to be
accessed is not connected to the slot of the host
apparatus and is not stored in the wafer cassette
stocker, the host apparatus causes a wafer transport
device to transport the first semiconductor wafer from
15 a wafer stocker to a cassetter, causes the cassetter to
accommodate the first semiconductor wafer in a cassette
case and causes the wafer cassette transport device to
transport a wafer cassette to be accessed including the
first semiconductor wafer to the slot of the host
20 apparatus, and to connect it thereto.